MICRO-ELECTRO-MECHANICAL MIRROR DEVICES HAVING A HIGH LINEAR MIRROR FILL FACTOR

Abstract

An array of movable MEMS mirror devices is provided having a high linear mirror fill factor. The array includes a base structure and selectively movable mirror structures pivotally mounted on the base structure. Each mirror structure is pivotally supported by a flexure connected to the base structure. The mirror structures each include a reflective surface portion, which is arranged in close proximity to the reflective surface portions of other mirror structures and in a generally linear alignment, forming a row structure. The flexures supporting adjacent mirror structures are staggered on opposite sides of the row structure.